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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Ryoji HOSHI et al.

Application No.: New U.S. National Stage of PCT/JP03/08671

Filed: January 4, 2005

Docket No.: 122336

For: A SILICON WAFER FOR EPITAXIAL GROWTH, AN EPITAXIAL WAFER, AND
A METHOD FOR PRODUCING IT

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please consider the following:

Amendments to the Claims as reflected in the listing of claims;

Remarks.